

Notice of References Cited

Application/Control No.

10/549,683

Applicant(s)/Patent Under
Reexamination
SUDA ET AL.

Examiner

MATTHEW J. SONG

Art Unit

1792

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U.S. PATENT DOCUMENTS

*		Document Number	Date	Name	Classification
		Country Code-Number-Kind Code	MM-YYYY		
	A	US-			
	B	US-			
	C	US-			
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FOREIGN PATENT DOCUMENTS

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NON-PATENT DOCUMENTS

*	Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)				
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V	Kugimiya et al., "Si-Beam Radiation Cleaning in Molecular beam epitaxy," Japanese Journal of Applied Physics Vol 24, No. 5, May 1985, pp 564-567.				
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.